

Docket No.: 50432-067



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kai YANG, et al.

Serial No.: 09/817,056

Filed: March 27, 2001

For: STABILIZING FLUORINE ETCHING OF LOW-K MATERIALS

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: Group Art Unit: 2811
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: Examiner: H. Vu
:

#8
Election
FJONES
8-2-02

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
Washington, DC 20231

Sir:

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In the Office Action dated June 25, 2002, the Examiner proposed a restriction requirement pursuant to 35 U.S.C. §121, required election of one of the following:

Group I. Claims 13 through 20 directed to a semiconductor device; or

Group II. Claims 1 through 12, directed to a method.

In response Applicants elect to prosecute method claims 1 through 12 (Group II).

Favorable consideration of method claims 1 through 12 is respectfully solicited.

To the extent necessary, a petition for an extension of time under 37 C.F.R. 1.136 is hereby made. Please charge any shortage in fees due in connection with the filing of this paper, including

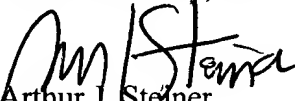
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09/817,056

extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

MCDERMOTT, WILL & EMERY


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Date: July 24, 2002